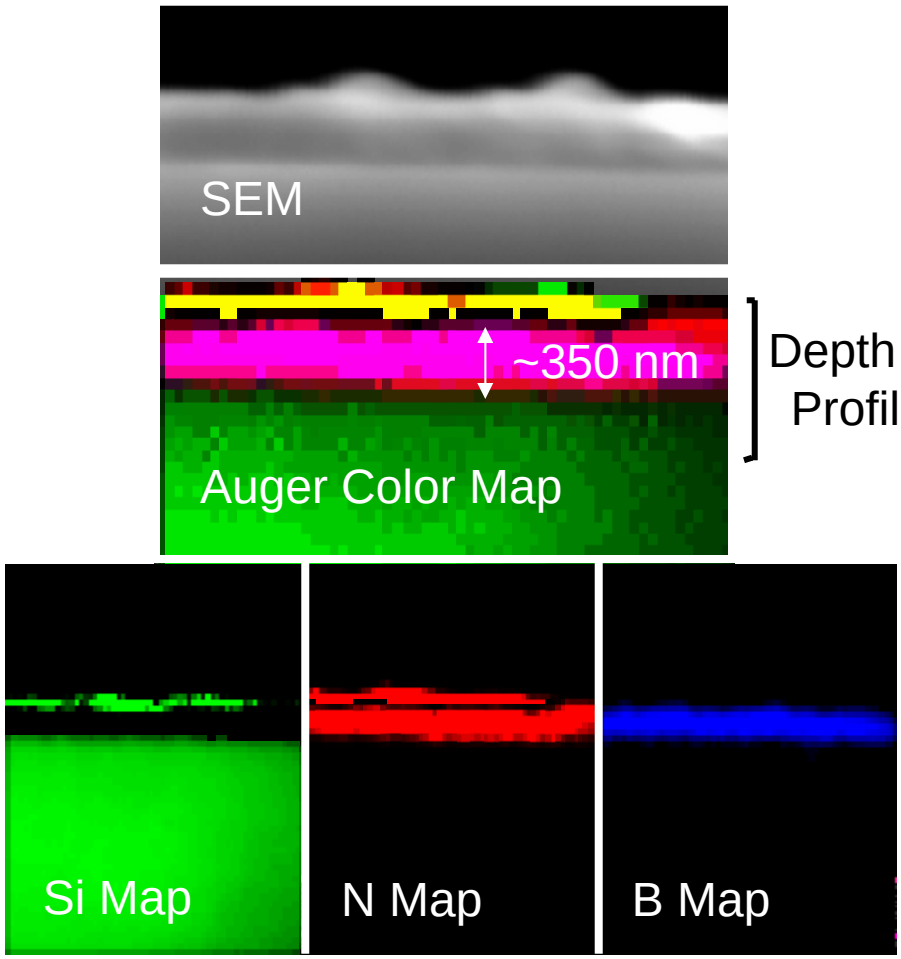
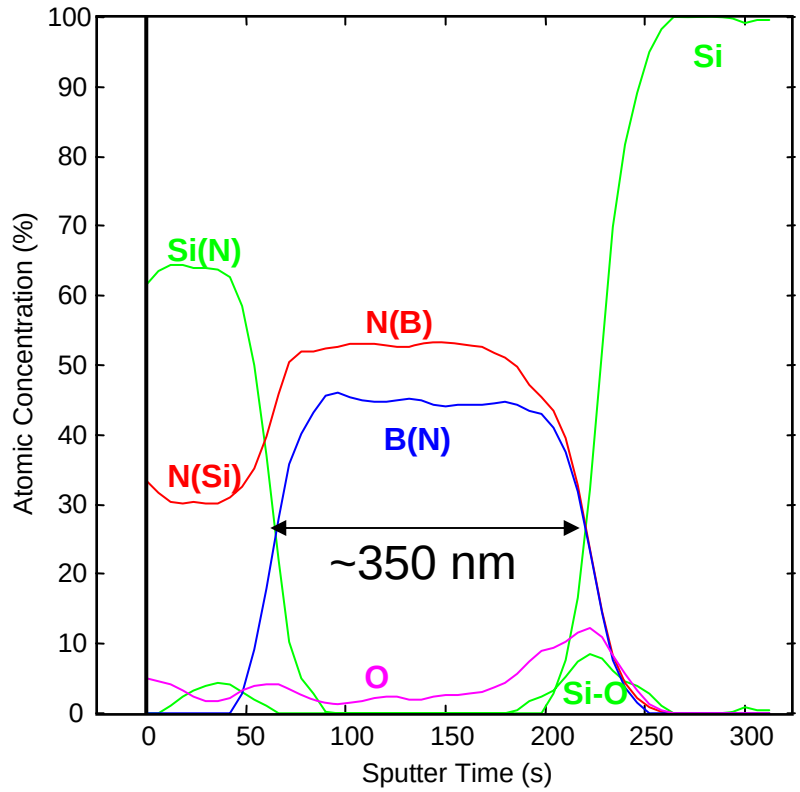
Determination of sputter rate using depth profiling and Auger mapping

(D. Petrak, Synterials - MAUC)





Depth profile through CVD deposited Si_xN_y/BN film on Si